

# EE 5211

# Analog Integrated Circuit Design

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Fall 2012

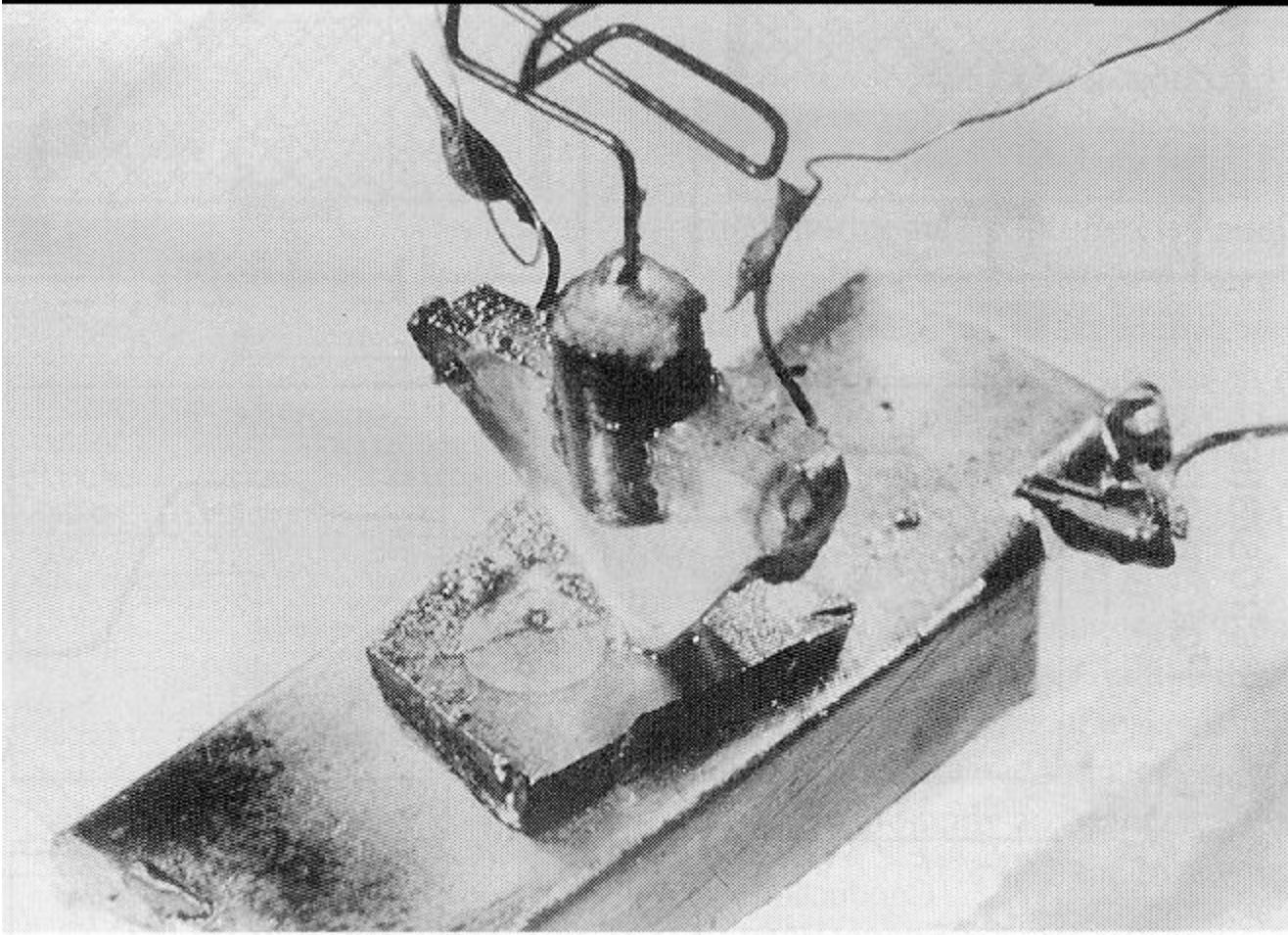
Today's topic:

1. Introduction to Analog IC
2. IC Manufacturing (Chapter 2)

# Introduction

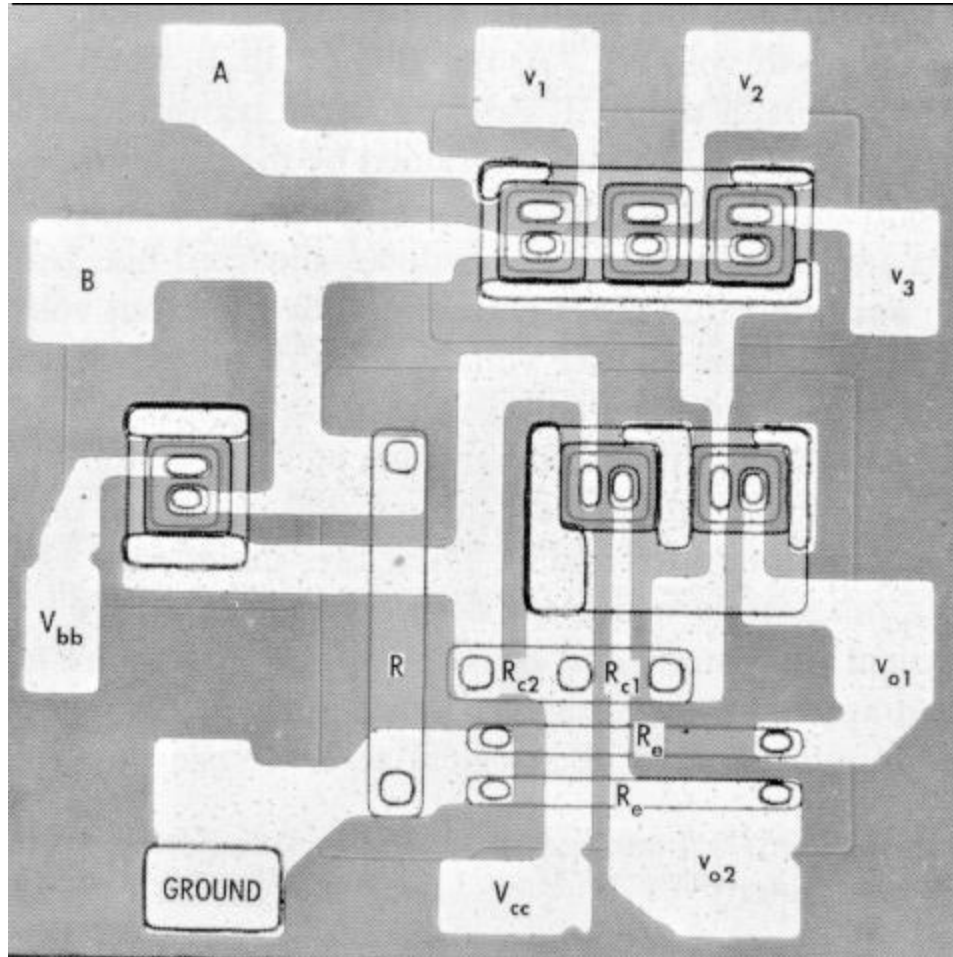
- What is Integrated Circuit (IC) vs discrete circuits? Why?

# The Transistor Revolution



First BJT transistor  
Bell Labs, 1948

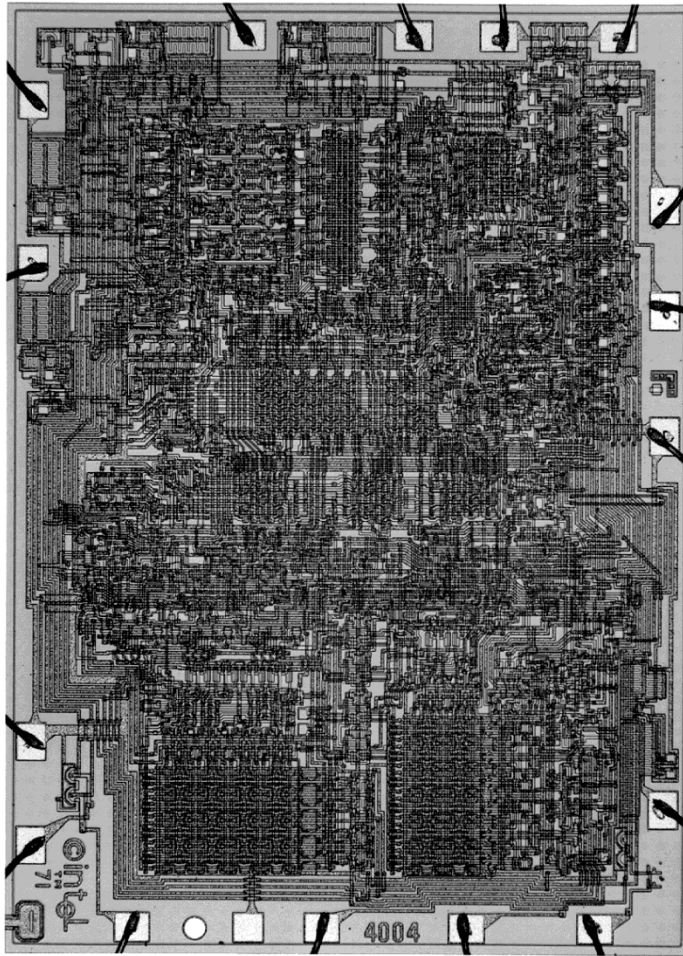
# The First Integrated Circuit



Bipolar logic  
1960's

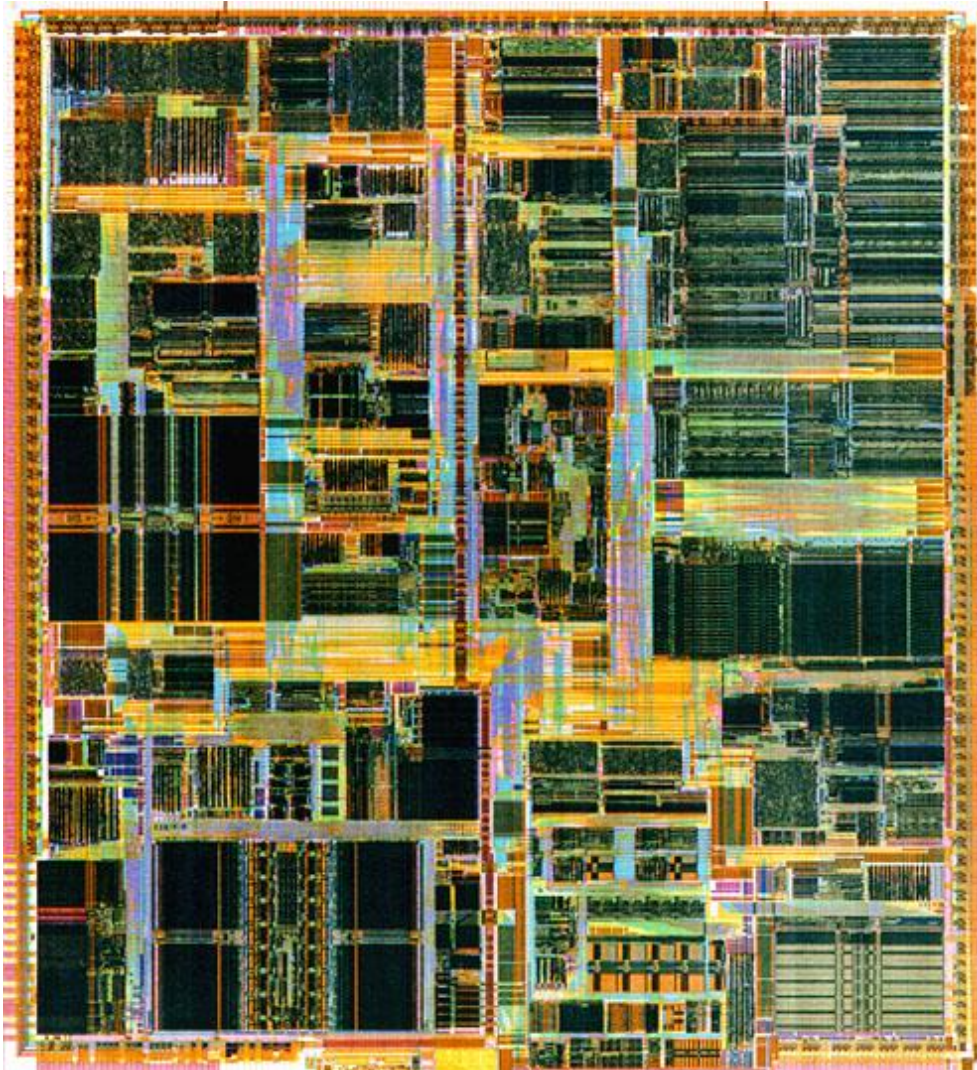
ECL 3-input Gate  
Motorola 1966

# Intel 4004 Micro-Processor



1971  
1000 transistors  
< 1MHz operation  
10 $\mu$ m technology

# Intel Pentium (IV) microprocessor



2001  
42 Million transistors  
1.5 GHz operation  
0.18 $\mu$ m technology

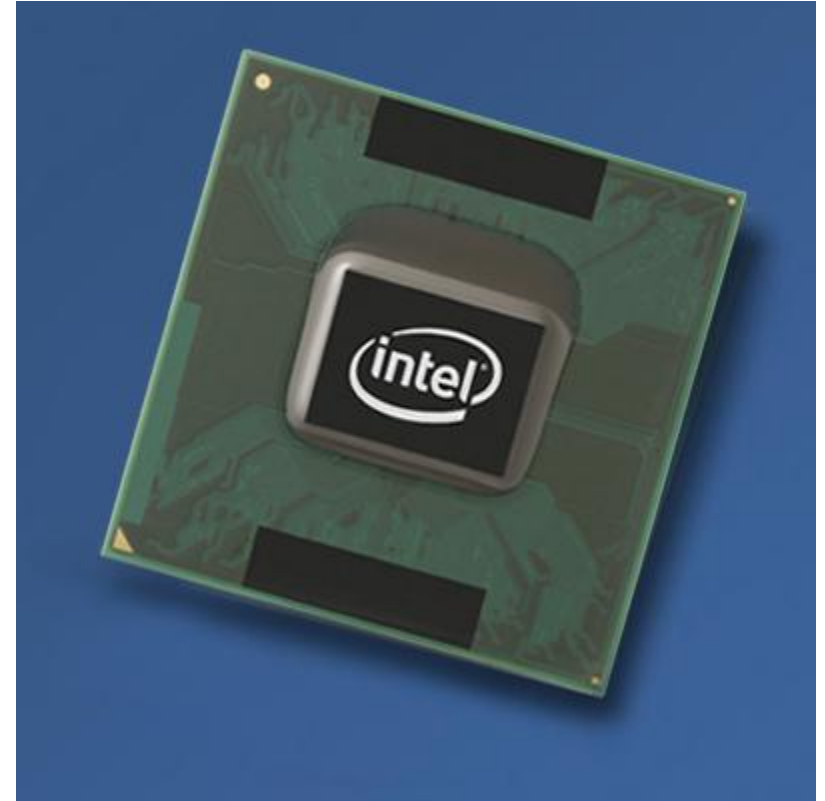
# Intel Core™2 Duo Processor

2006

291 Million transistors

3 GHz operation

65nm technology





# More recent

2007

>800 Million transistors

2 GHz operation

45nm technology (the biggest change in CMOS transistor technologies in 40 years)



2011 2<sup>nd</sup>-generation Core i7

1.2 Billion transistors

3.3 GHz operation

32nm technology

# Introduction

- What is Analog Integrated Circuit (IC) vs Digital Integrated Circuit?

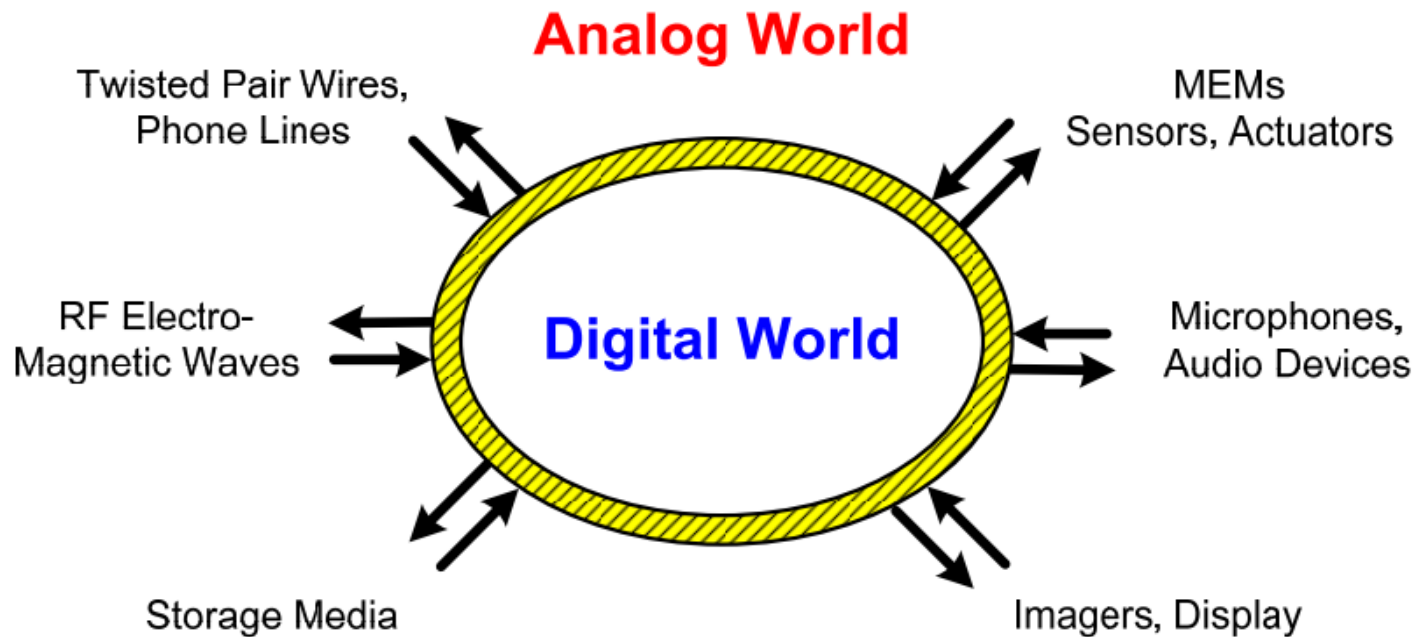
# Analog versus Digital

- Information-bearing signals can be either analog or digital.
- Analog signal takes on a continuous range of amplitude values.
- Whereas digital signal takes on a finite set of discrete values (often binary) and frequently changes values only at uniformly spaced points in time
- Analog circuits:
  - circuits that connect to, create and manipulate arbitrary electrical signals
  - circuits that interface to the continuous-time “real” world

# So why do we still need analog?

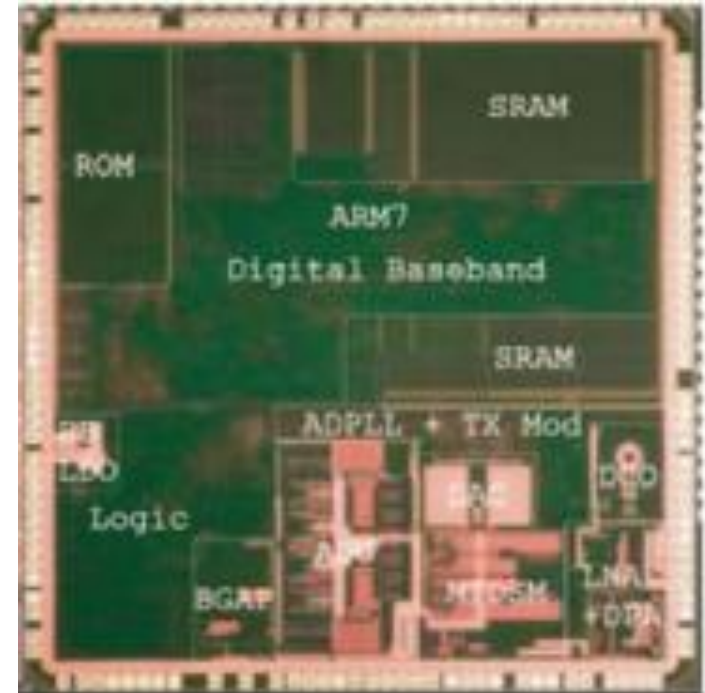
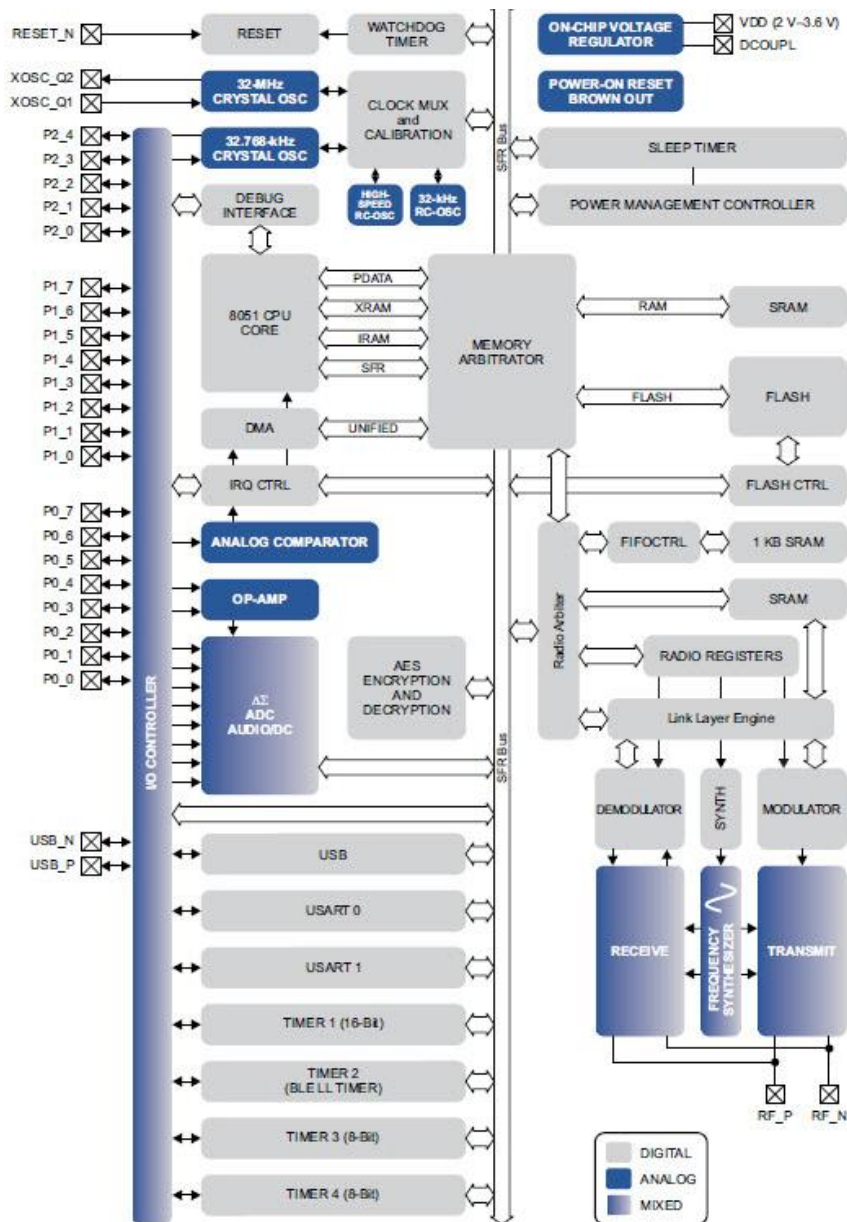
- The real world is analog (voice, light, heart-beat...)
- Many of the inputs and outputs of electronic systems are analog signal
- Many electronic systems, particularly those dealing with low signal amplitudes or very high frequency required analog approach
- *Lots of most challenging design problems are analog*
- *Good analog circuit designers are scarce (very well compensated, gain lots of respect, regarded as “artists” because of the “creative” circuit design they do...)*

# Why A-D Interface?



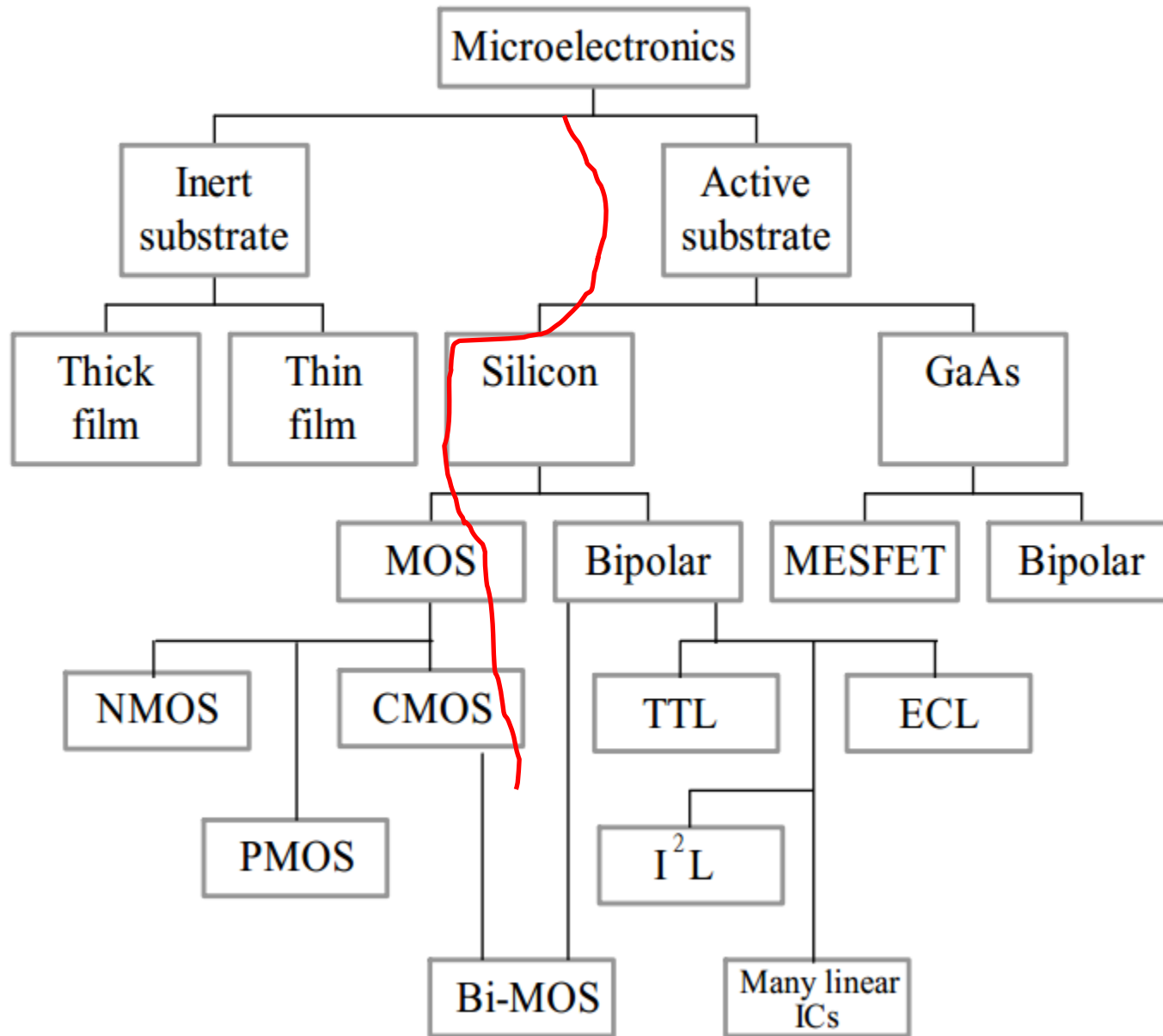
- Nature is analog, not digital.
- A-D interface's role is "translator".

The dominance of digital circuits actually *increased* the amount of analog electronics in existence. Nowadays, most electronic systems on a single chip contain both analog and digital (called *Mixed-signal SoC (System on Chip)*)



From Texas Instruments

# Major Process Used in IC Fabrication



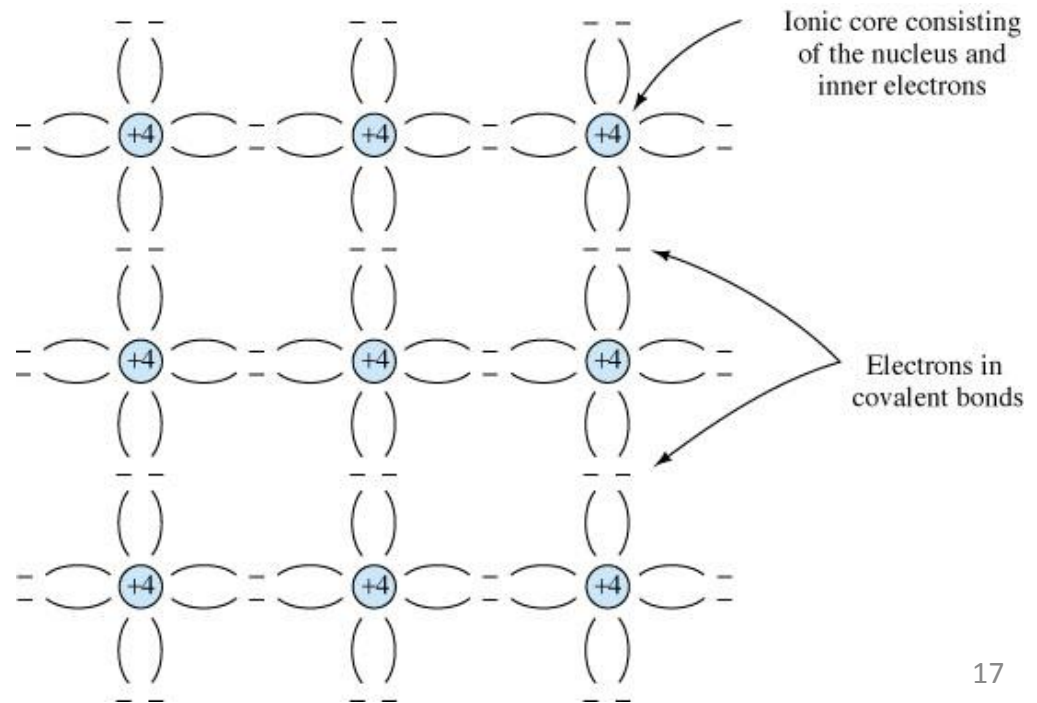
# Basic semiconductor concepts

- A qualitative knowledge of semiconductor physics helps us understand the characteristics of diodes and other devices discussed later.
- Several materials are most often used for fabrication of solid-state electronic devices: silicon (Si), germanium (Ge) and gallium arsenide (GaAs)
- Silicon is most used, therefore a focus is put on Si in the discussion.



# Intrinsic silicon

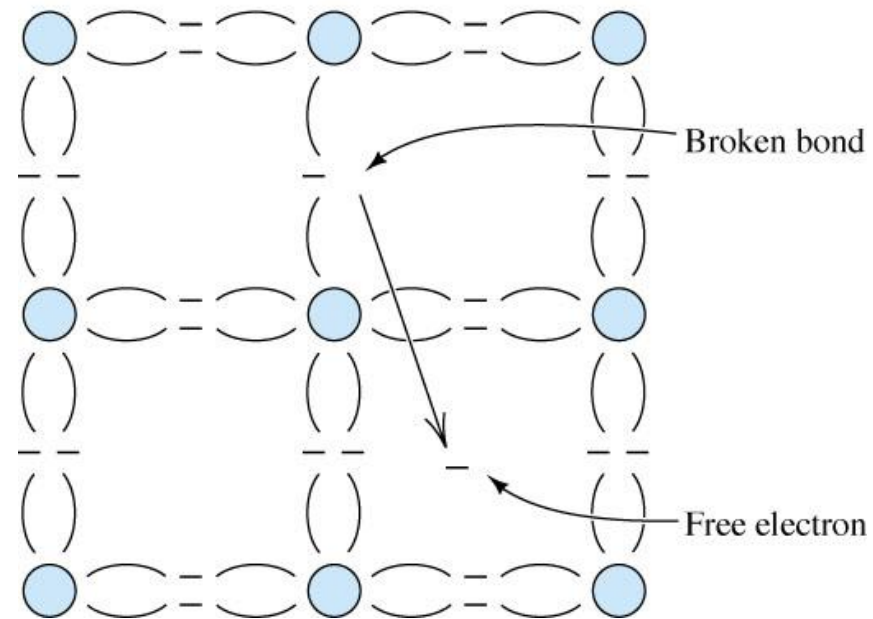
- Bohr model of an isolated silicon atom consists of a nucleus containing 14 protons.
- 14 electrons surround the nucleus in specific orbits (known as shells)
- The innermost shell (lowest energy) consists of 2 orbits. The next higher energy shell contains 8 orbits. The remaining 4 electrons occupy the outmost shell (called valence shell).
- In intrinsic (pure) silicon, each atom takes up a lattice position having four neighboring atoms. Each pair of neighboring atoms forms a covalent bond consisting of two electrons orbiting the pair.



**Figure 3.36** Intrinsic silicon crystal.

# Intrinsic silicon II

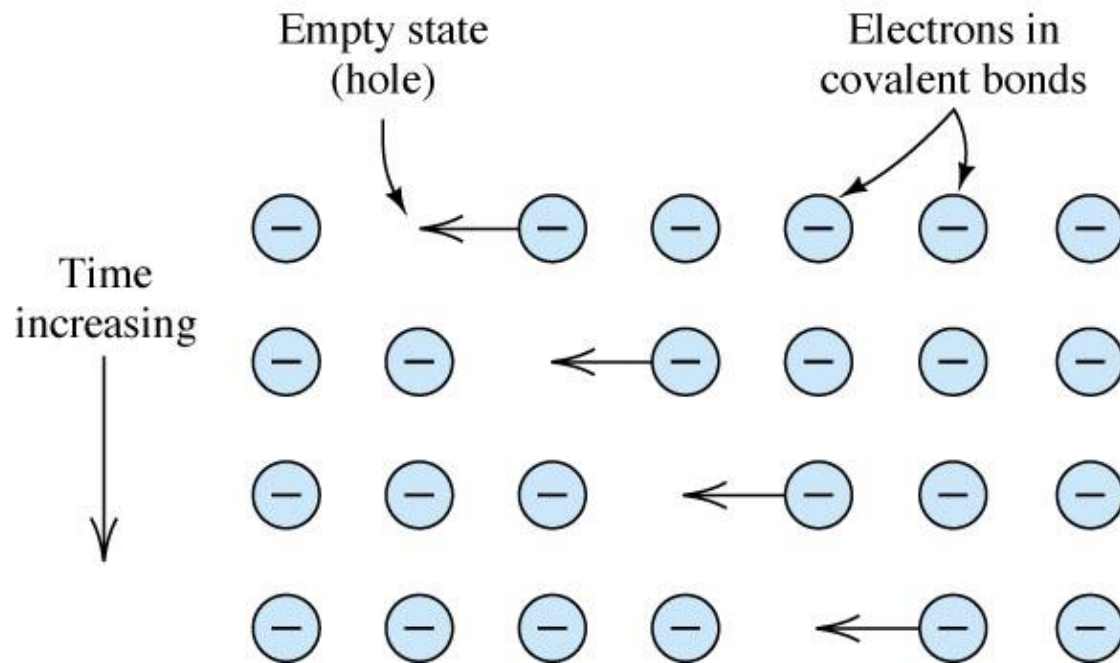
- At absolute zero temperature, electrons take the lowest energy state available and all valence electrons are bound in covalent bonds and are not free to move. (silicon is an electrical insulator in this condition).
- However, in room temperatures (300K), a small fraction of the electrons gain sufficient thermal energy to break loose from the covalent bonds. These free electrons can easily move through the crystal.
- If voltage is applied to intrinsic silicon, current flows. However, the number of free electrons is small compared to a good conductor (so called semiconductor).
- Quantitatively, at room temperature only  $1.45 \times 10^{10}$  free electrons per  $\text{cm}^3$  among  $5.0 \times 10^{22}$  atoms.



**Figure 3.37** Thermal energy can break a bond, creating a vacancy and a free electron, both of which can move freely through the crystal.

# Intrinsic silicon III: conduction by holes

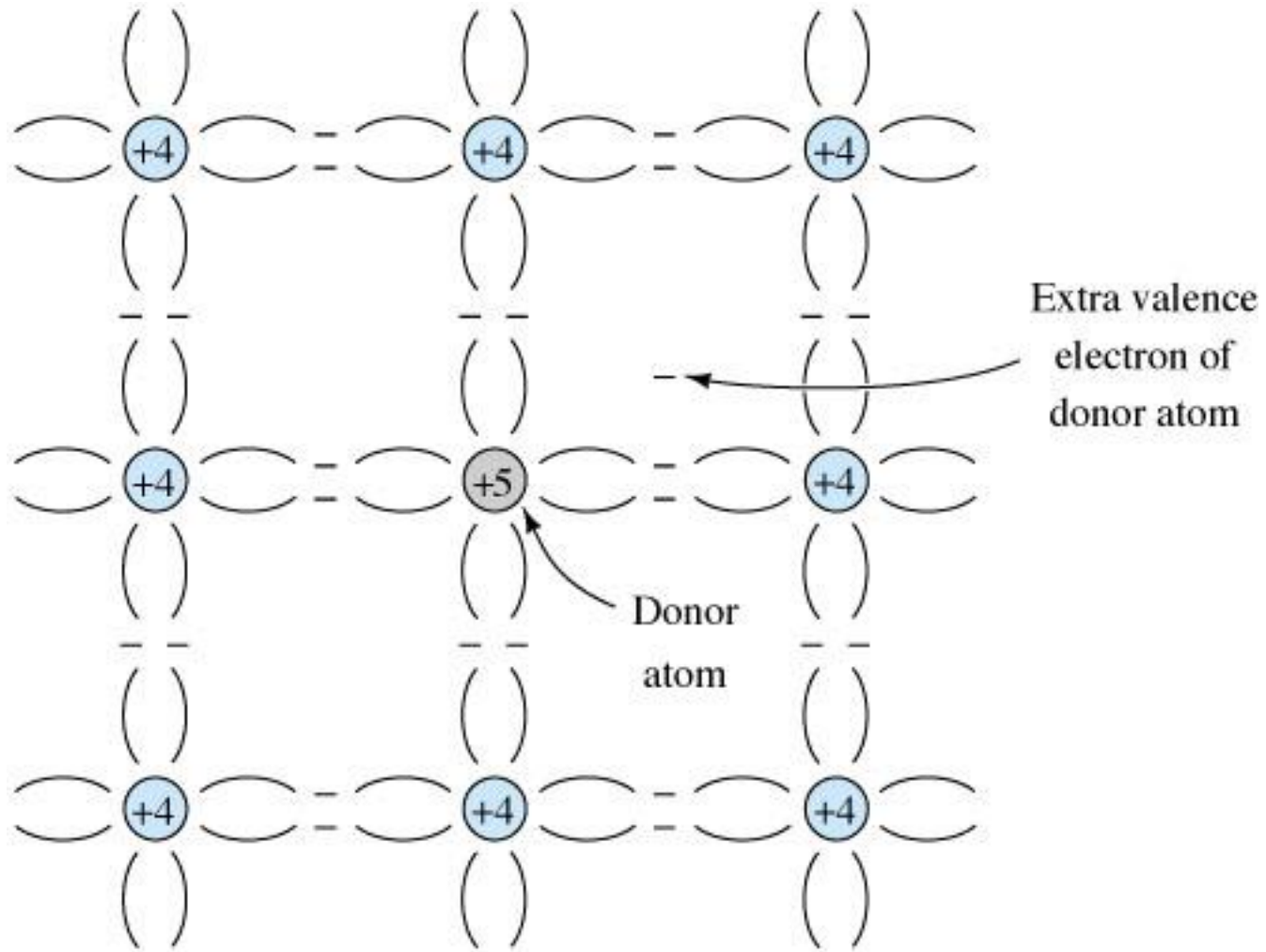
- Free electrons are not the only means by which current flows in intrinsic silicon.
- Though it is the electrons that actually move, the vacancy or the hole can be thought of as a positive charge carrier that is free to move in the silicon. (bound electron can move only if a vacancy exists nearby).
- In an intrinsic silicon, an equal number of holes and free electrons are available, or  $n_i = p_i$  where  $n_i$  denotes the free electron concentration and  $p_i$  hole concentration.
- When an electric field is applied to the intrinsic silicon, both types of carriers contribute to current flow.



**Figure 3.38** As electrons move to the left to fill a hole, the hole moves to the right.

# N-type semiconductor

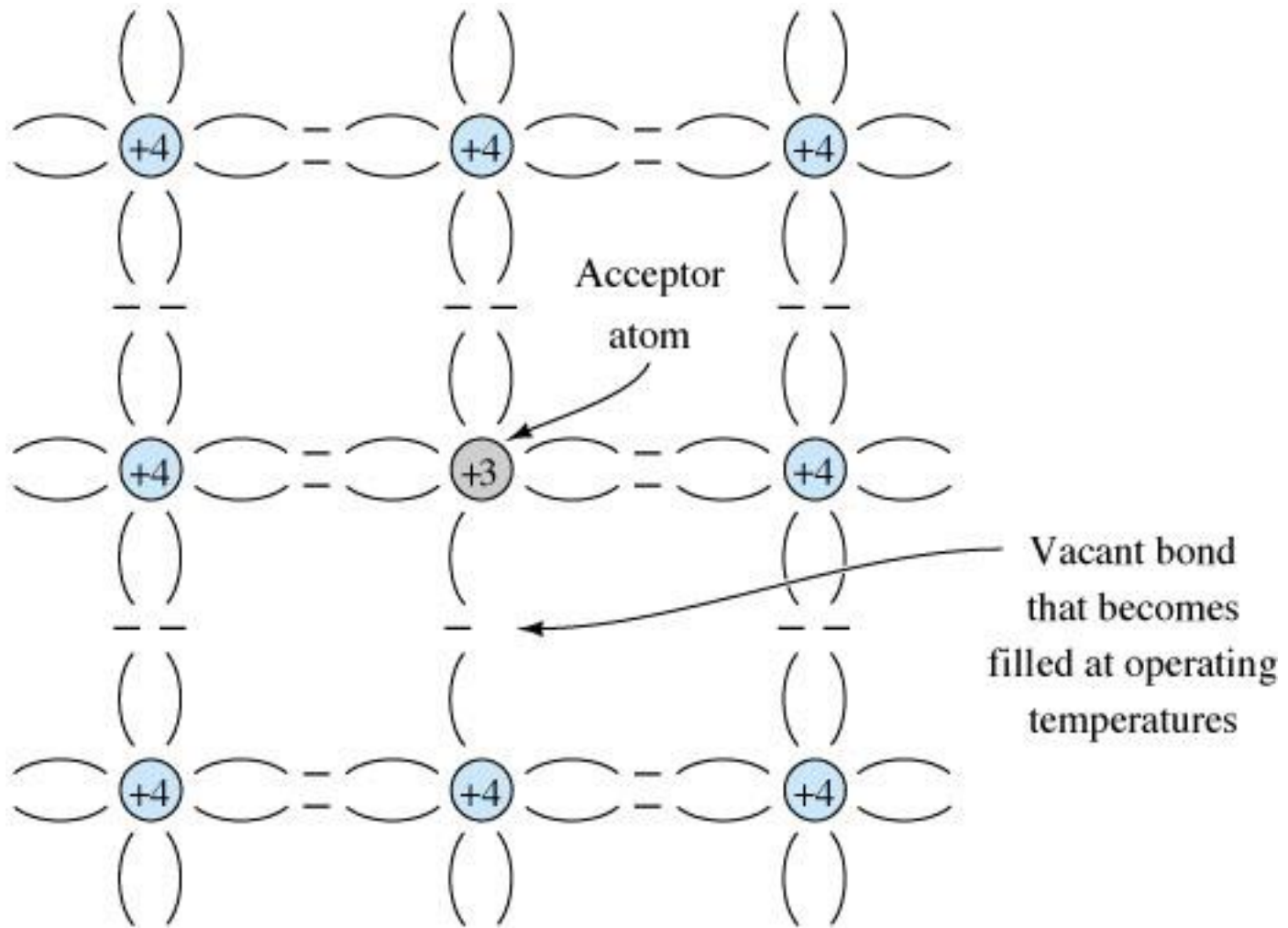
- Adding small amounts of suitable impurities to the crystal dramatically affects the relative concentration of holes and electrons. The resulting semiconductor is called extrinsic semiconductor.
- A material of impurity, such as **phosphorus**, have 5 valence electrons. It forms covalent bonds with their four neighbors and the 5<sup>th</sup> is only weakly bound to the atom.
- At certain temperature, the 5<sup>th</sup> electron can easily breaks its bond with the atom and becomes a free electron. However, a hole is not created by the impurity atom as the positive charge that balances the free electron is locked in the ionic core of the atom (or no covalent bond vacancy)
- Impurities that does this is known as donors to silicon and the resulting material is called N-type semiconductor material.
- In N-type material, conduction is mainly due to free electrons. Thus free electrons are called majority carriers and holes called minority carriers.
- Donor atoms giving up their 5<sup>th</sup> electron is said to become ionized. Positive charge is associated with each ionized atom.
- Net charge concentration is zero, ie. positive charge of ionized donors and holes is equal to negative charge of electrons.



**Figure 3.39** *n*-type silicon is created by adding valence five impurity atoms.

# P-type semiconductor

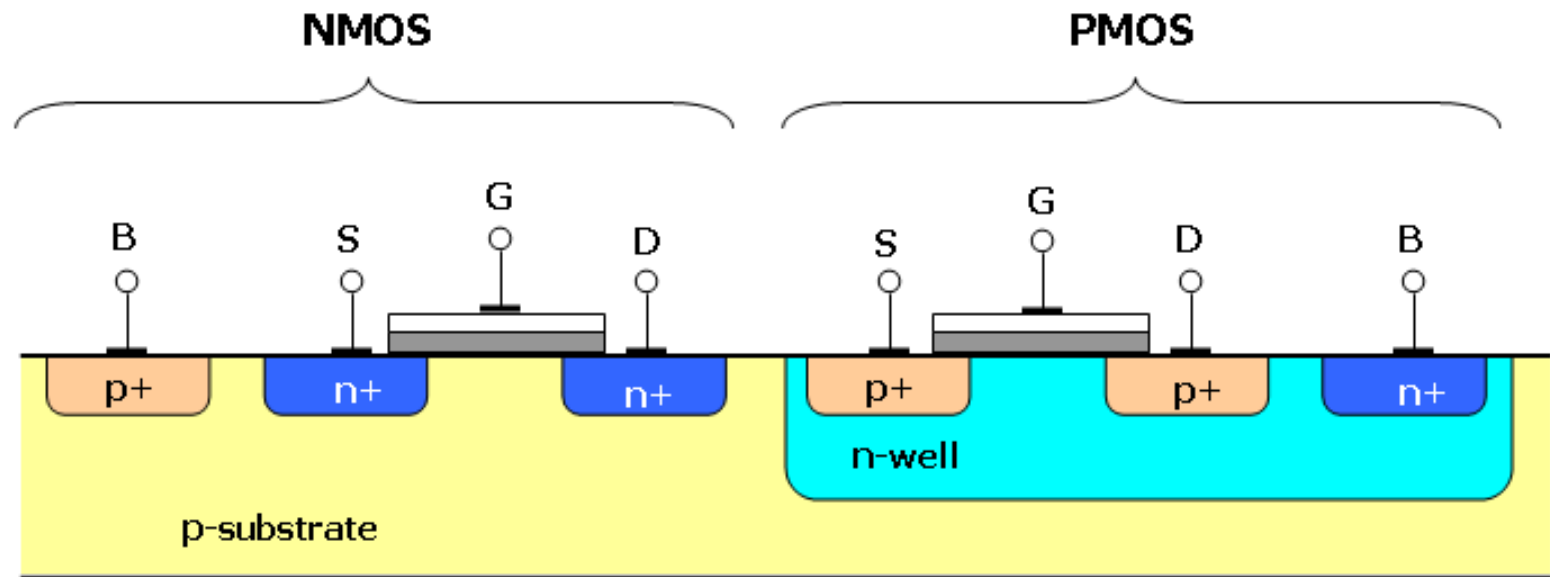
- In contrast to N-type semiconductor, impurity such as boron can be added to intrinsic silicon to form P-type semiconductor.
- Each impurity atom forms covalent bonds with three of its neighbors, but it does not have the 4<sup>th</sup> electron to complete the bond with the 4<sup>th</sup> neighbor.
- At usual operating temperatures, an electron from a nearby silicon atom moves in to fill the fourth bond of each impurity atom. This creates a hole moving freely through the crystal .
- Since the electron is bound to the ionized impurity atom, conduction in P-type material is mainly due to holes. Holes are called majority carriers and electrons minority carriers.
- The impurities are called acceptors because they accept an extra electron.
- Ionized impurity atom has negative charge. The concentration of holes is equal to the sum of concentration of free electrons and that of acceptor atoms.



**Figure 3.40** *p*-type silicon is created by adding valence three impurity atoms.

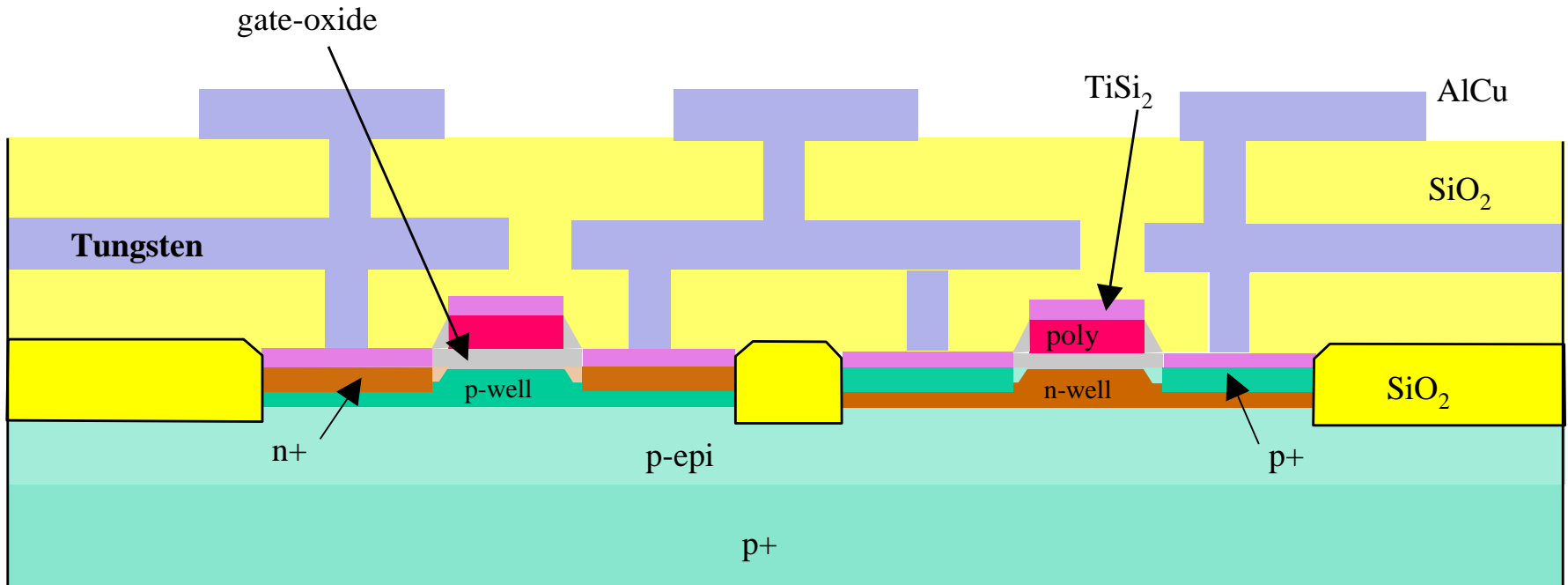
# Basic IC circuit component: MOS transistor

MOS: Metal Oxide Semiconductor



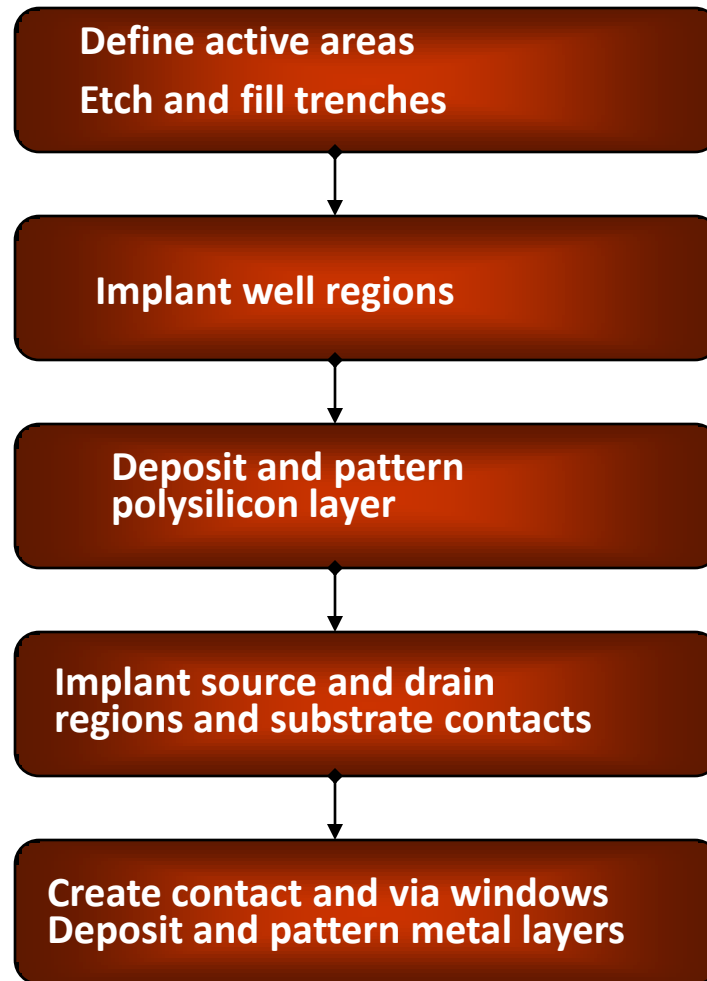


# Modern dual-well CMOS Process

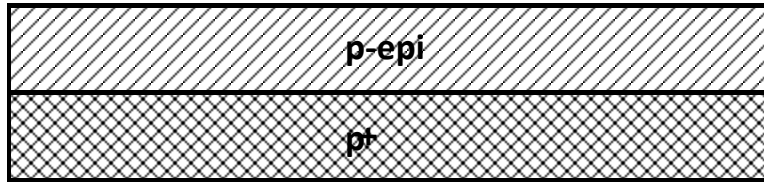


Dual-Well Trench-Isolated CMOS Process

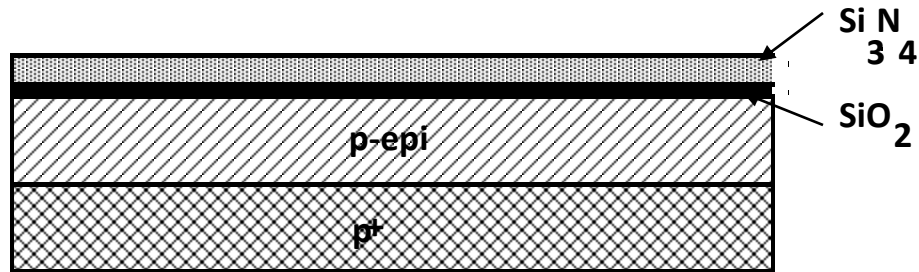
# CMOS Process at a Glance



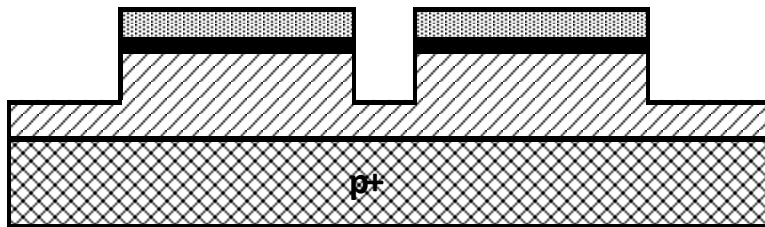
# CMOS Process Walk-Through



(a) Base material: p+ substrate with p-epi layer

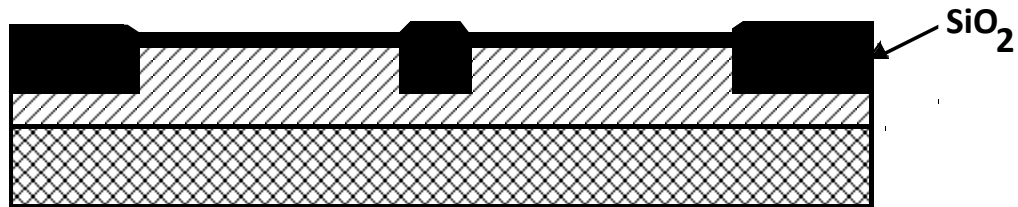


(b) After deposition of gate-oxide and sacrificial nitride (acts as a buffer layer)

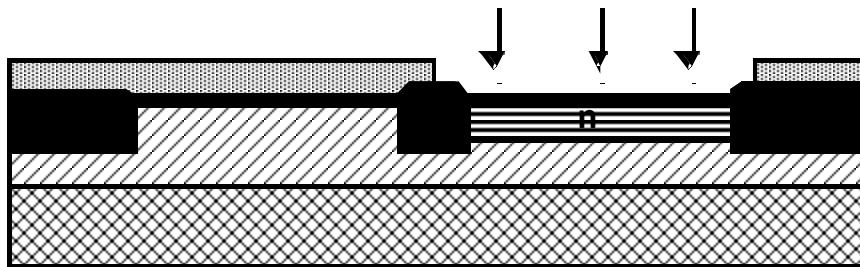


(c) After plasma etch of insulating trenches using the inverse of the active area mask

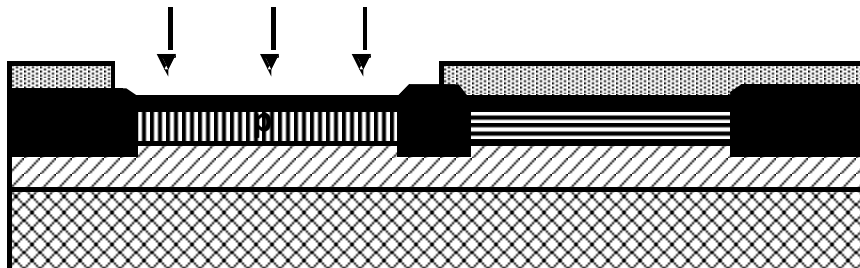
# CMOS Process Walk-Through



(d) After trench filling, CMP planarization, and removal of sacrificial nitride

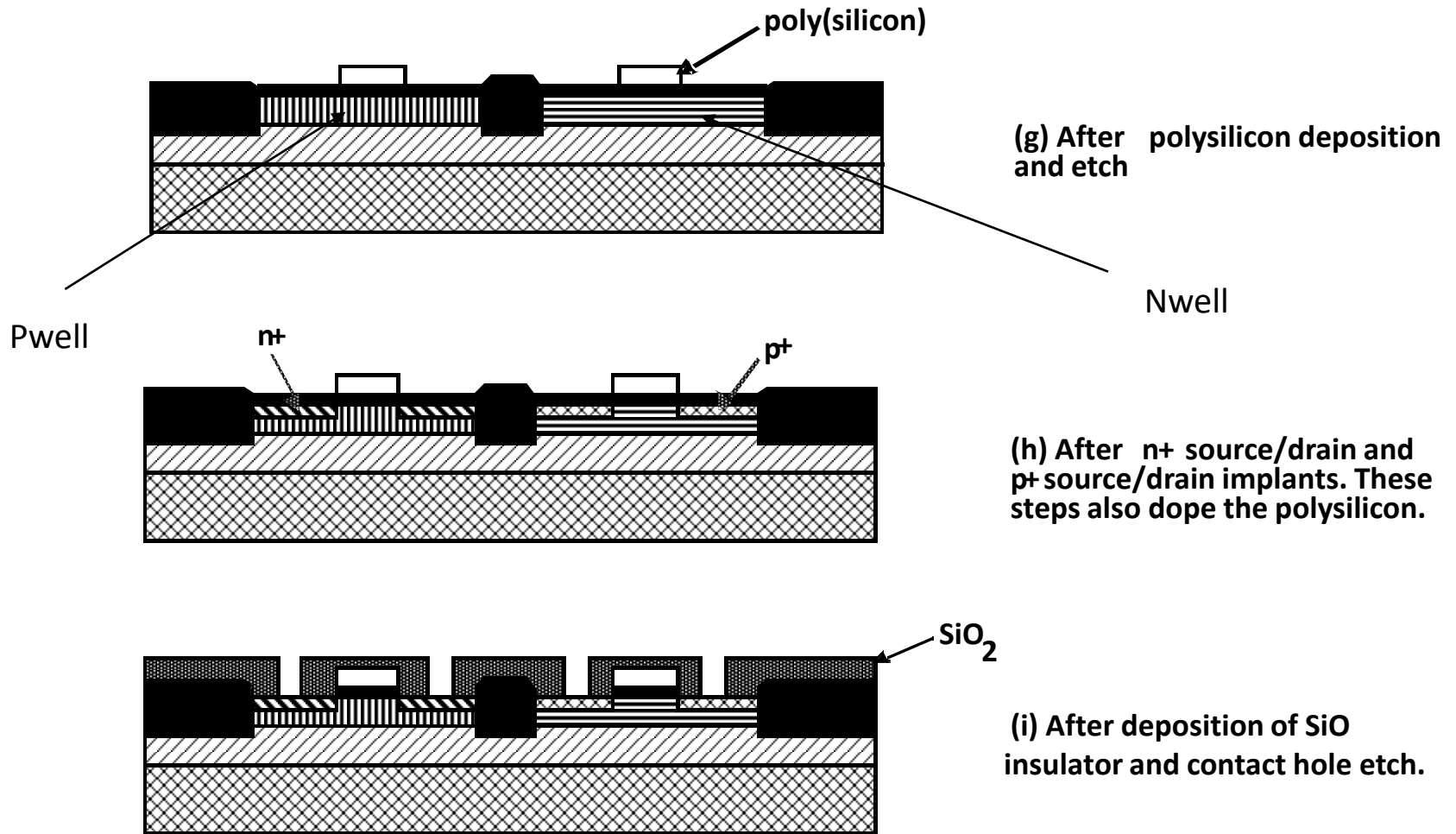


(e) After n-well and  $V_{Tp}$  adjust implants

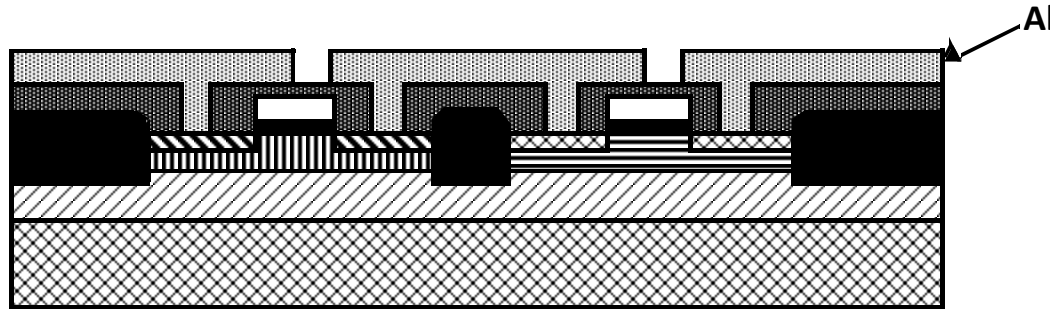


(f) After p-well and  $V_{Tn}$  adjust implants

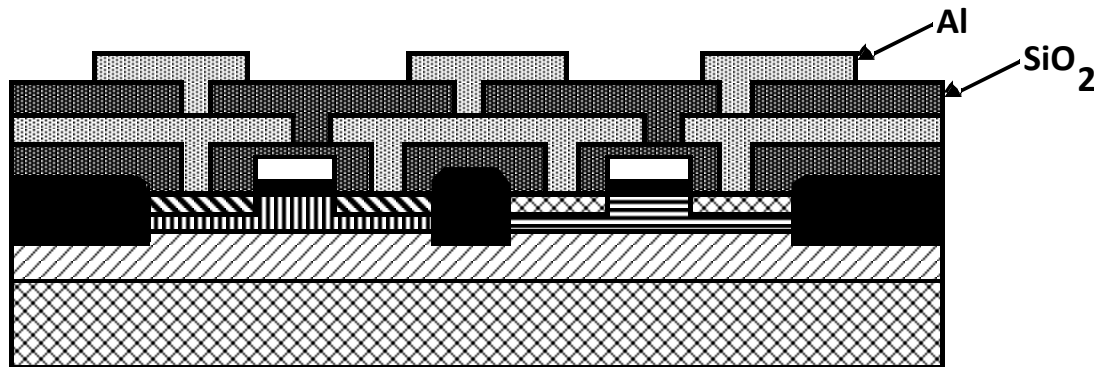
# CMOS Process Walk-Through



# CMOS Process Walk-Through



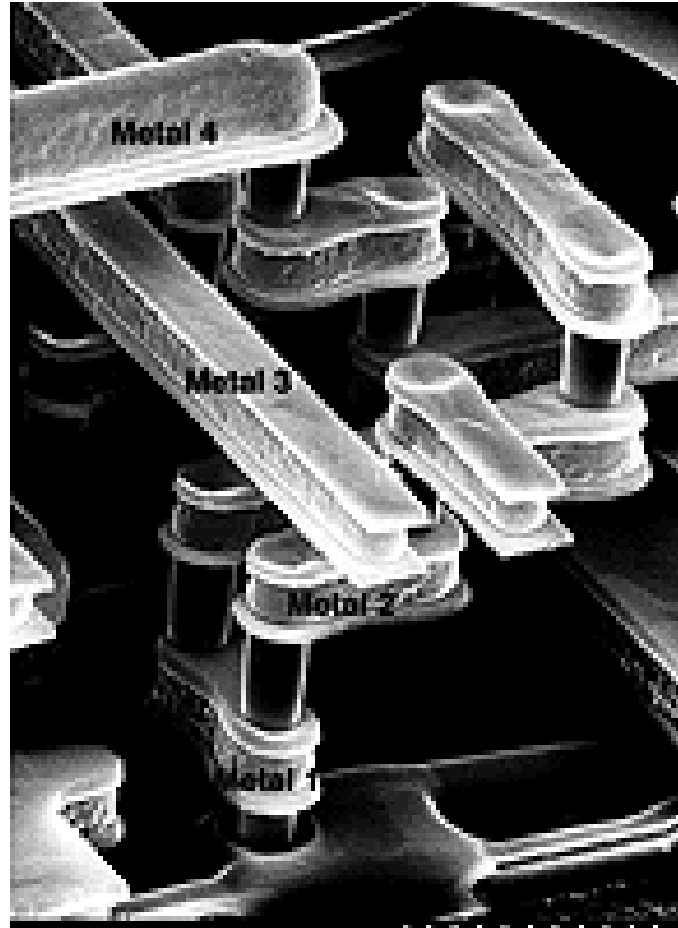
(j) After deposition and patterning of first Al layer.



(k) After deposition of SiO<sub>2</sub> insulator, etching of via's, deposition and patterning of second layer of Al.

2

# Advanced Metallization


















# Design Rules



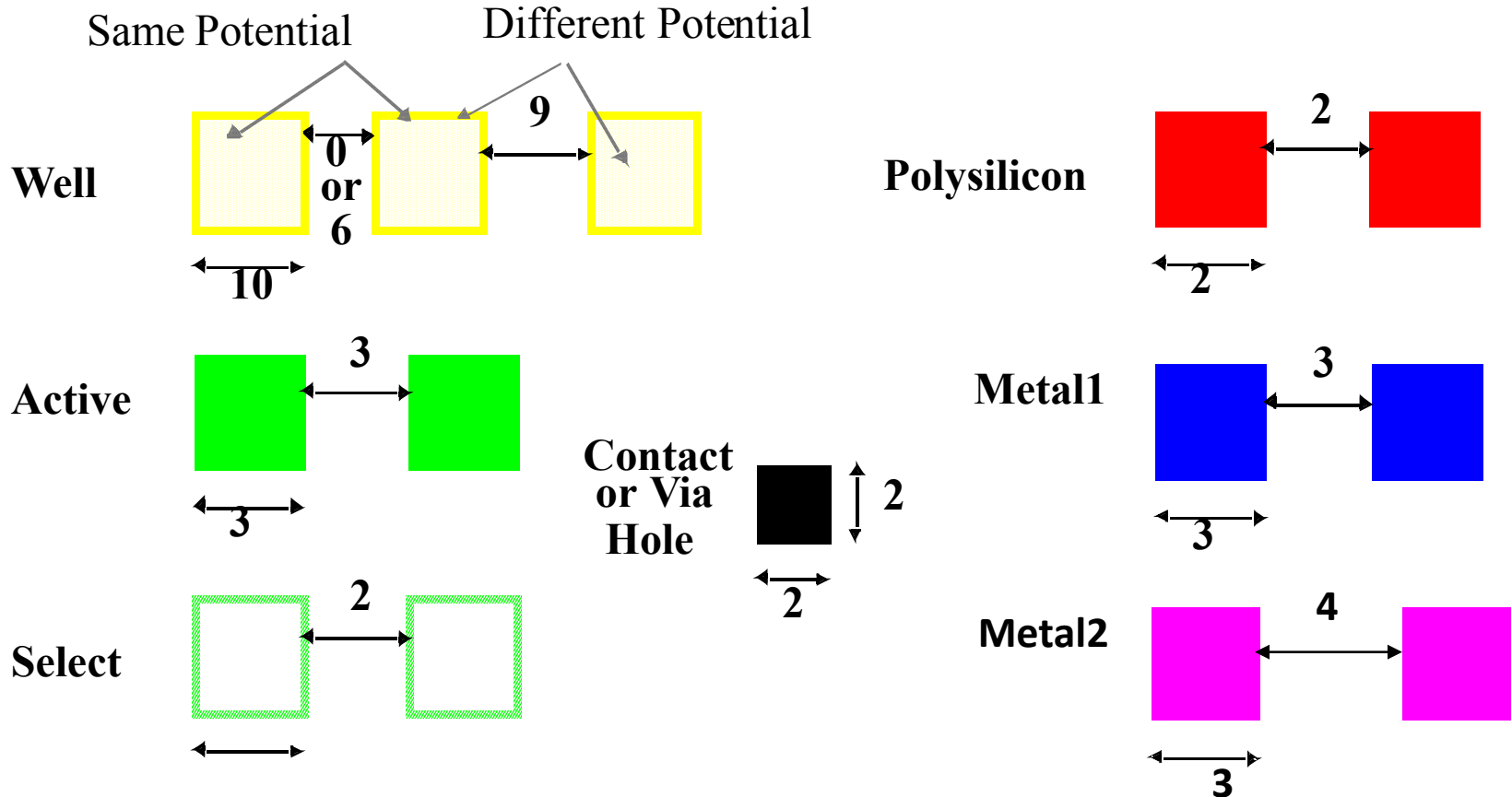
# Design Rules

- Interface between designer and process engineer
- Guidelines for constructing process masks
- Unit dimension: Minimum length
  - scalable design rules: lambda parameter (SCMOS SUBMICRON Design Rules)  
Technology=2 lambda
  - absolute dimensions (micron rules)

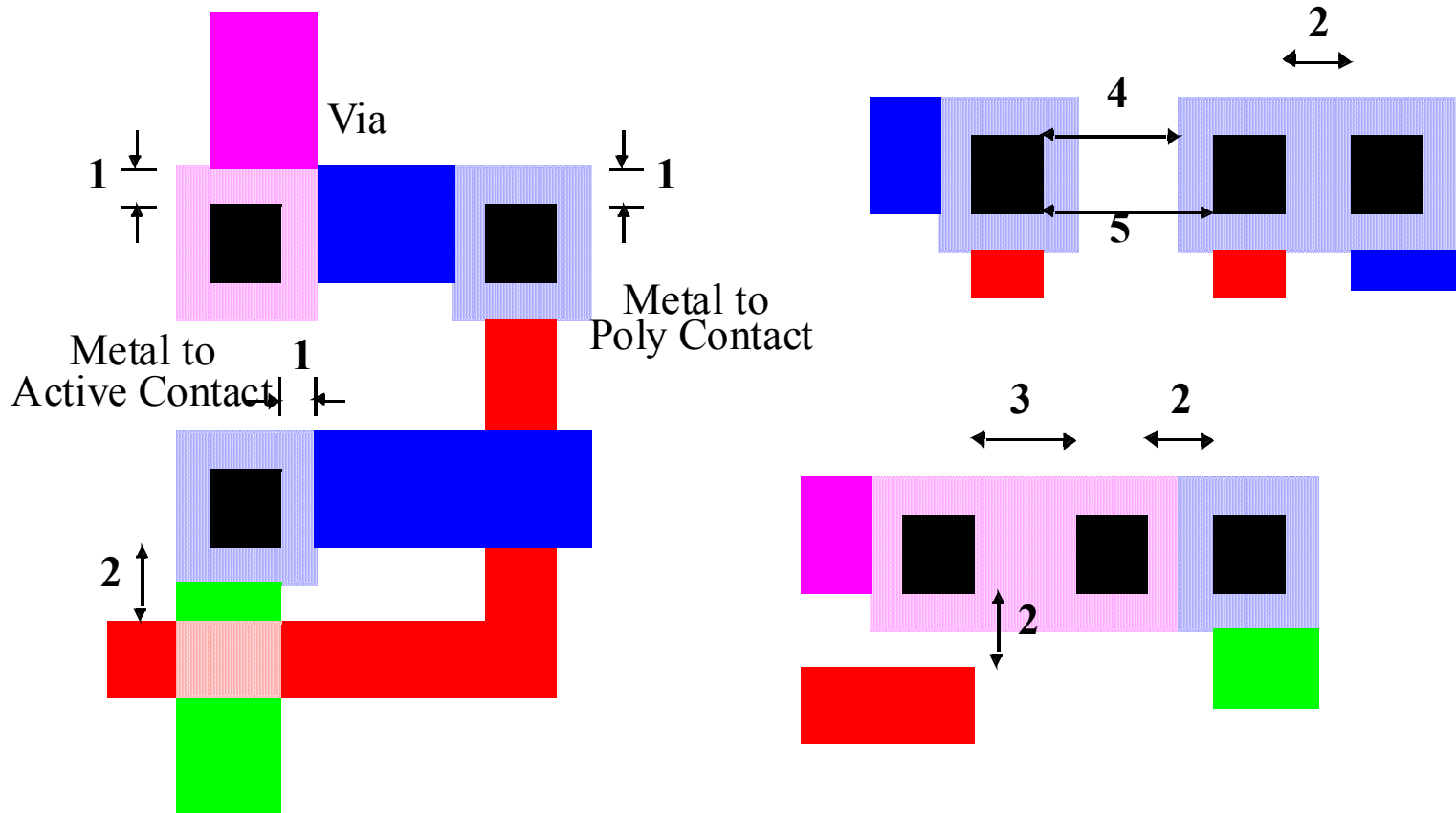
# Layers in 0.25 $\mu\text{m}$ CMOS process

Layer Description	Representation				
metal	 m1	 m2	 m3	 m4	 m5
well	 nw				
polysilicon	 poly				
contacts & vias	 ct	 v12,v23,v34,v45	 nwc	 pwc	
active area and FETs	 ndif	 pdif	 nfet	 pfet	

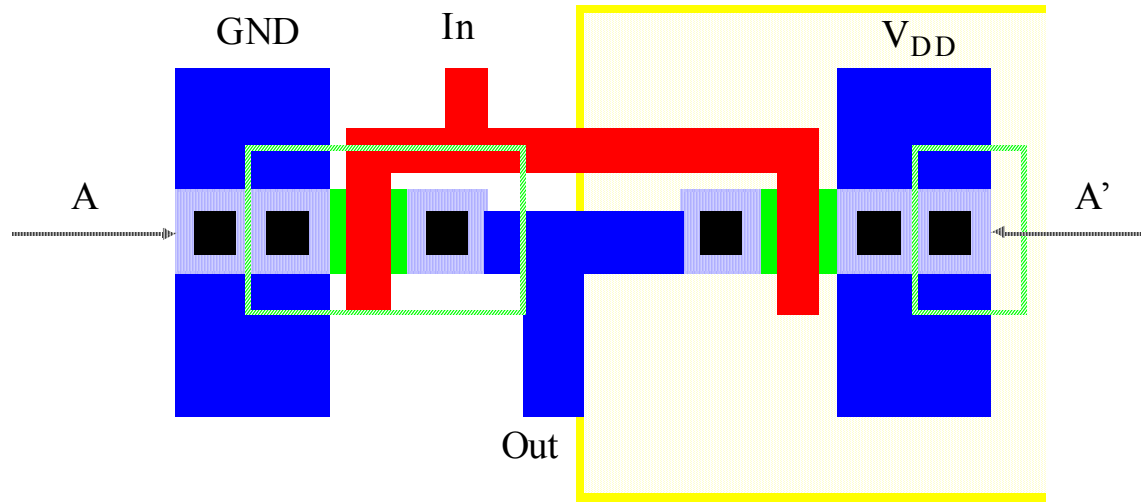
# Intra-Layer Design Rules



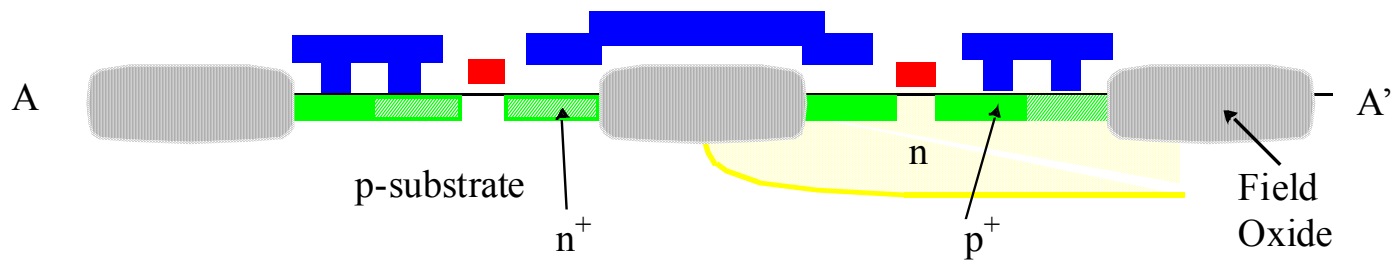
# Vias and Contacts



# CMOS Inverter Layout



(a) Layout



(b) Cross-Section along A-A'

# Layout Editor

LSW

Virtuoso® Layout Editing: tsmc025stdlib INVX1 layouttest

X: -9.300 Y: -7.275 (F) Select: 0 DRD: OFF dX: dY: Dist: Cmd: 2

Tools Design Window Create Edit Verify Connectivity Options Routing NCSU Help

Sort Edit Help

pwell drw

NCSU\_TechLib\_tsmc03

Show Objects

Inst Pin

AV NV AS NS

pwell drw

nwell drw

active drw

tactive drw

nactive drw

pactive drw

nselect drw

pselect drw

poly drw

metal1 drw

metal2 drw

metal3 drw

metal4 drw

metalcap drw

metal5 drw

cc drw

via drw

via2 drw

via3 drw

via4 drw

glass drw

nodrc drw

nolpe drw

pad drw

vdd

gnd

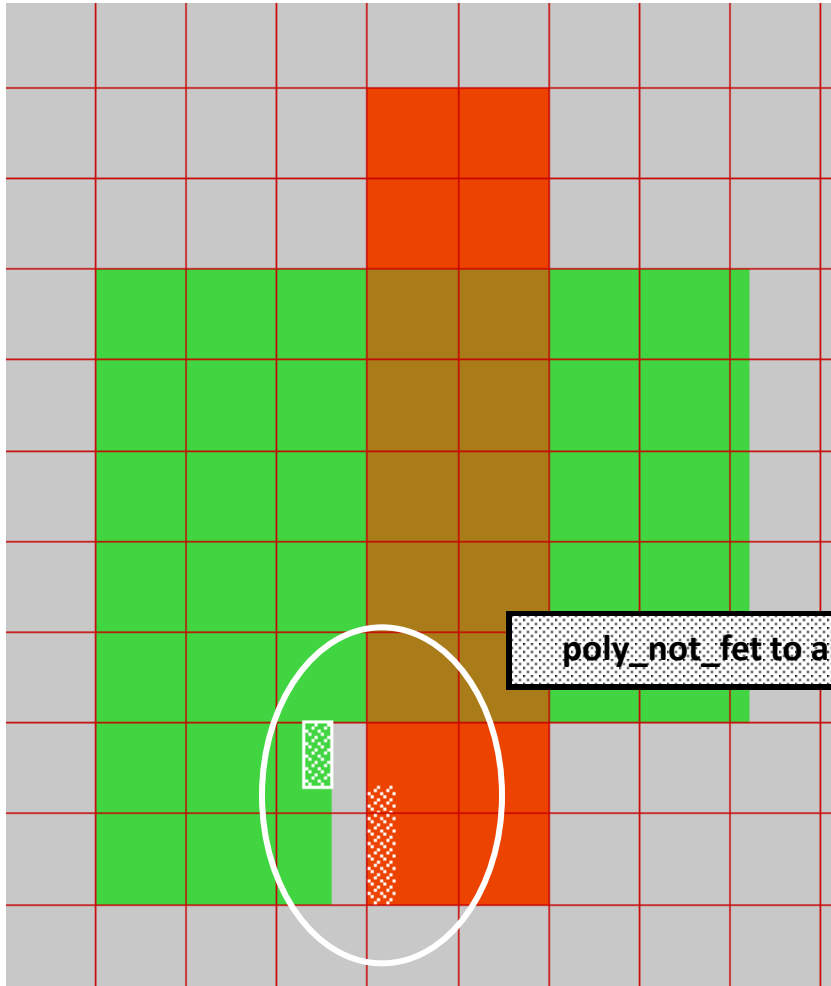
A

Y

mouse L: showClickInfo() M: leHiMousePopUp() R: leHiEditDisplayOptions()

The image shows a screenshot of the Virtuoso Layout Editor interface. The main window displays a PCB layout with a grid background. A central vertical red line represents a power plane or signal trace. On either side of this line, there are several rectangular components or pads. The top components are labeled 'vdd' and the bottom components are labeled 'gnd'. The layout is composed of various layers, each with a distinct color and pattern, as shown in the legend on the left. The legend includes layers like 'pwell', 'nwell', 'active', 'tactive', 'nactive', 'pactive', 'nselect', 'pselect', 'poly', 'metal1' through 'metal5', 'cc', 'via' through 'via4', 'glass', 'nodrc', 'nolpe', and 'pad'. The interface also shows a menu bar at the top with options like 'Tools', 'Design', 'Window', 'Create', 'Edit', 'Verify', 'Connectivity', 'Options', 'Routing', 'NCSU', and 'Help'. A status bar at the bottom provides information about the current tool and mouse actions.

# Design Rule Check

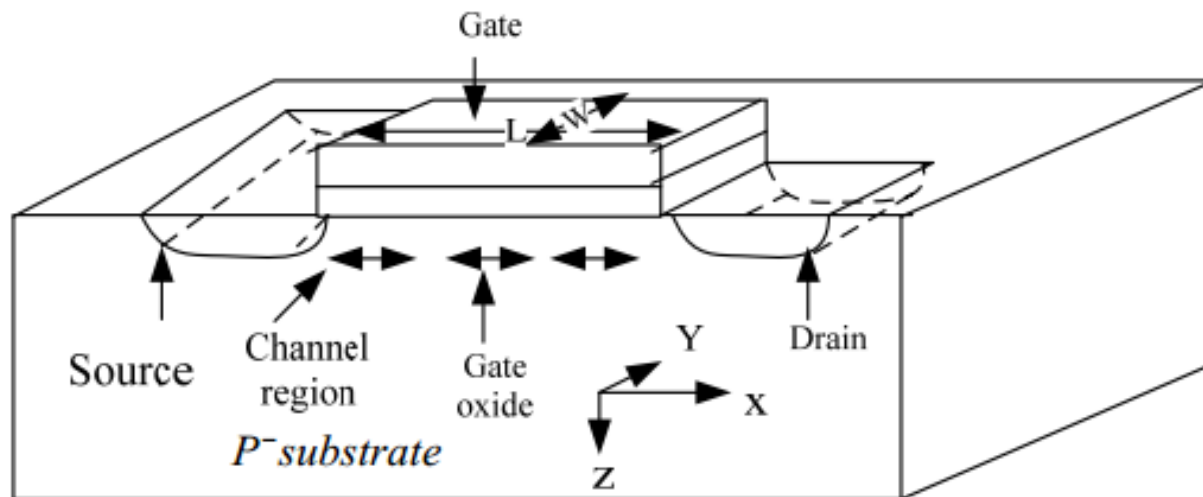


poly\_not\_fet to all\_diff minimum spacing = 0.14 um.

# Feature size

The minimum feature size a CMOS process is roughly the minimum allowable value for L and W. For example, in a 5 $\mu$ m process the minimum permissible value of L and W would be 5 $\mu$ m.

Simplified 3-dimensional view of a FET



Feature size keeps scaling down in the past years, eg. 2 $\mu$ m, 1 $\mu$ m, 0.5 $\mu$ m, 0.35 $\mu$ m, 0.25 $\mu$ m, 0.18 $\mu$ m, 0.13 $\mu$ m, 90nm, 65nm, 45nm, 33nm, 23nm, ....